

**ELECTRONIC DEVICE FOR A LITHOGRAPHY MASK CONTAINER,  
SEMICONDUCTOR MANUFACTURING SYSTEM, AND METHOD**

Abstract of the Disclosure

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An electronic device (205) is attached to a container (200) that carries a lithography mask (201) through a semiconductor factory (100) from a first station (110) to a second station (120). In the device, a receiver unit (210) receives first data (111) indicating how the first station has used the mask in a first process; a memory unit (220) temporarily stores the first data; a processor unit (230) processes the first data and provides second data (122) indicating how the second station uses the mask in a second future process; and a transmitter unit (240) transmits the second data to the second station or to a factory host.

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